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a cantilever attached to the second positioning unit, the cantilever having a tip, the first and second positioning units configured to position the tip over a device under test (DUT), the probe apparatus including an electrical signal path between the tip of cantilever and probe station user instruments; and

a motion sensor configured to detect motion of the cantilever.

23. (Amended) A method for probing a device under test (DUT), comprising:

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EPA  
mounting a probe apparatus to <sup>an existing</sup> a probe station platform of a probe station so as to <sup>with probing capability</sup>

provide additional probing capability to the probe station;

coarsely positioning with a first positioning unit of the probe apparatus a tip of a cantilever of the probe apparatus over a surface of the DUT;

finely positioning with a second positioning unit attached to the first positioning unit the tip of the cantilever of the probe apparatus over the surface of the DUT; and

sensing motion of the cantilever.

30. (Amended) A probe apparatus, comprising:

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first positioning means for coarse positioning mounted to <sup>an existing</sup> a probe station platform of a <sup>with probing capability</sup> probe station so as to provide additional probing capability to the probe station;

a probe arm attached to the coarse positioning means;

second positioning means for fine positioning attached to the probe arm;

a cantilever attached to the second positioning unit, the cantilever having a tip, the first and second positioning units configured to position the tip over a device under test (DUT), the probe apparatus including an electrical signal path between the tip of cantilever and probe station user instruments; and